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CONFIRMATION NO. 6821

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|-----------------------------|---------------------------------------|--------------|------------------------|--|
| SERIAL NUMBER 10/665,934 | FILING DATE 09/19/2003 RULE | CLASS 438 | GROUP ART UNIT 2823 | ATTORNEY DOCKET NO. APPM/7989/ETCH/SILICON/JB |
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APPLICANTS

Wei Liu, San Jose, CA;

David Mui, Fremont, CA;

** CONTINUING DATA ***** *BK, none*** FOREIGN APPLICATIONS ***** *BK, none*

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

** 12/11/2003

Foreign Priority claimed ☐ yes ☒ no
35 USC 119 (a-d) conditions met ☐ yes ☐ no ☐ Met after Allowance
Verified and Acknowledged *BK*
Examiner's Signature _____ Initials _____

STATE OR

SHEETS

TOTAL

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COUNTRY

DRAWING

CLAIMS

CLAIMS

CA

4

17

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ADDRESS

PATENT COUNSEL
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O. Box 450A
Santa Clara, CA
95052

TITLE

Method of controlling critical dimension microloading of photoresist trimming process by selective sidewall polymer deposition

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